

GECCO 2006: Evolutionary Computation in Practice: EC and IEC for MEMS Design

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Motivation

The Goals of this talk:

- Introduce field of MEMS
- Discuss issues of MEMS design
- Present work using EC for MEMS design



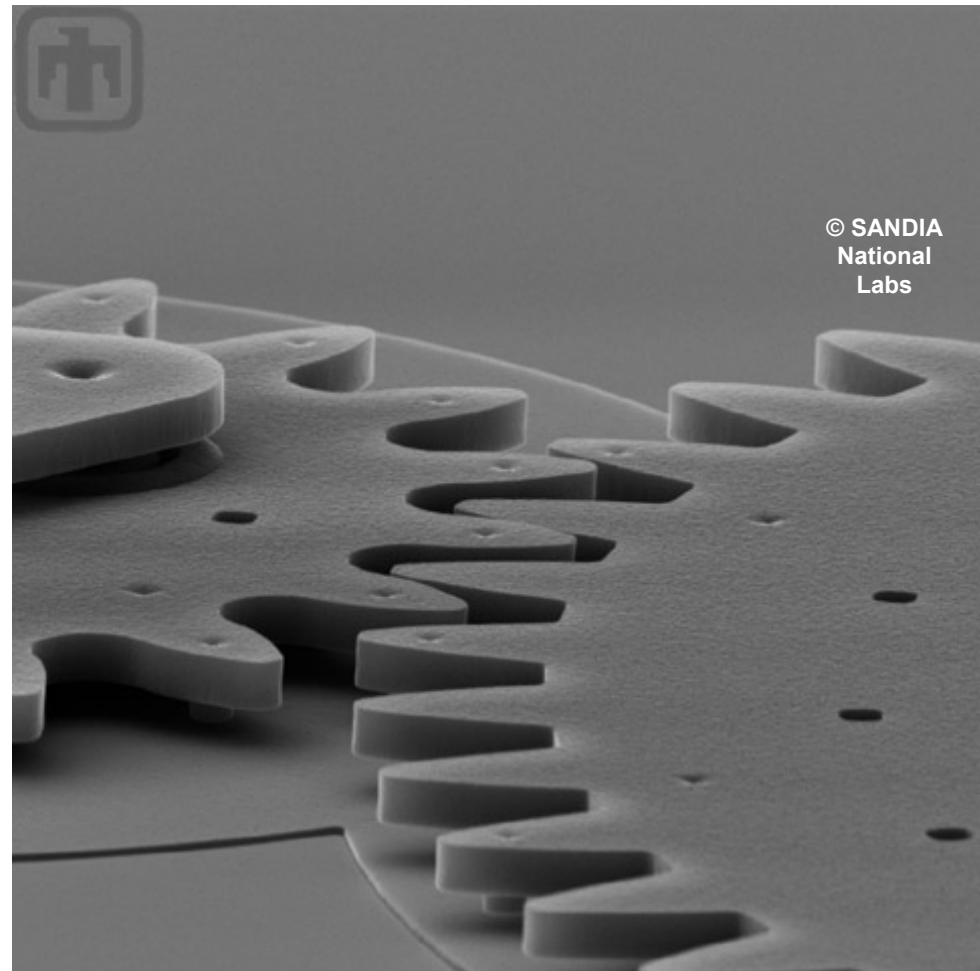
Contents

- What are MEMS?
- MEMS in our daily lives
- How are MEMS made?
- Simulation
- Design
- *EC* Synthesis for MEMS
- *IEC* Synthesis for MEMS



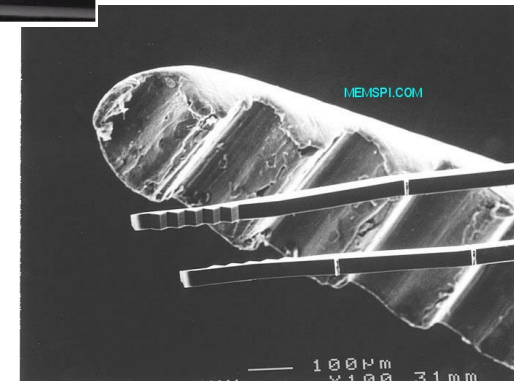
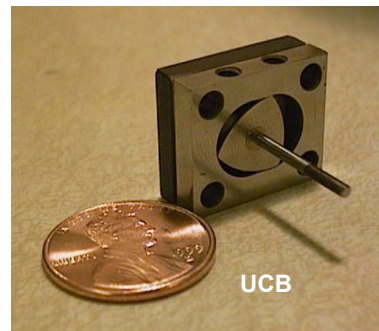
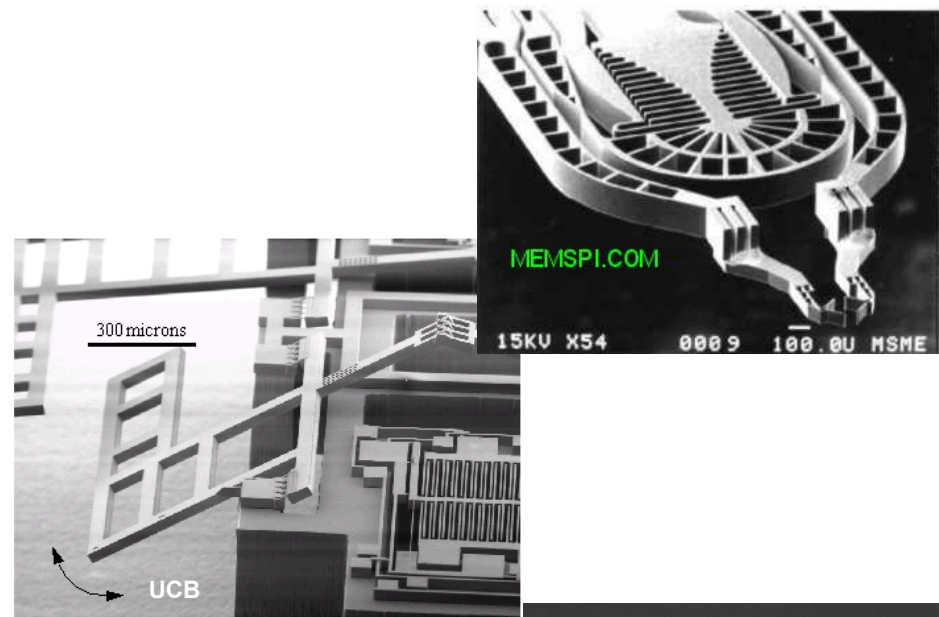
What are MEMS?

- Micro Electromechanical Systems or *Micromachines*
- Very small electromechanical devices made on silicon
- Microfabrication, like computer chips



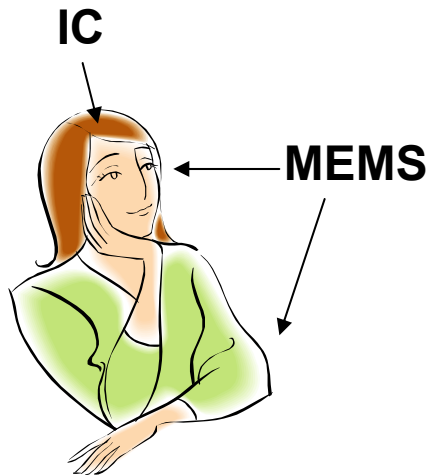
What are MEMS?

- Applications for
 - Sensors
 - Robotics
 - Communications
 - Printer heads
 - Biotechnology
 - Energy Generation
- Component sizes $< 10 \mu\text{m}$
- Device sizes $< 1 \text{ cm}$



What are MEMS?

- “Micro-Electro-Mechanical Systems (MEMS) is the integration of mechanical elements, sensors, actuators, and electronics.”



Integrated Circuits are the "**brains**" of a system and MEMS are "**eyes**" and "**arms**", to allow microsystems to *sense* and *control* the environment.

from <http://www.memsnet.org>

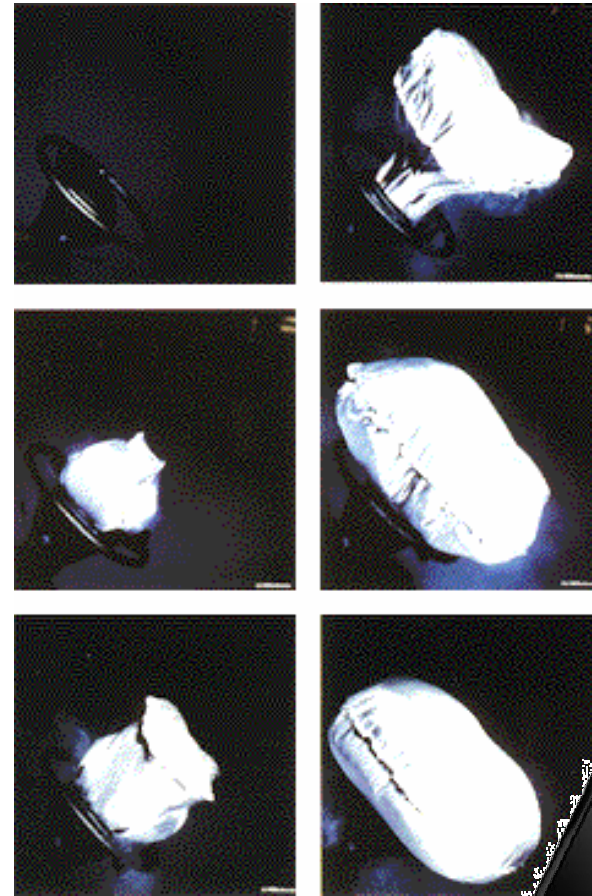
A few cases of MEMS already in our daily lives...

- MEMS Accelerometers
- MEMS Gyroscopes
- Digital Micromirror Arrays



MEMS Accelerometers

- Anywhere you need to measure motion
 - Car Airbags
 - when the car stops suddenly
 - Notebook PC
 - protect the hard drive



MEMS Accelerometers

IBM Active Protection System



IBM



Sudden acceleration in notebook's motion triggers a signal to temporarily park hard drive's read/write head

Active Protection System



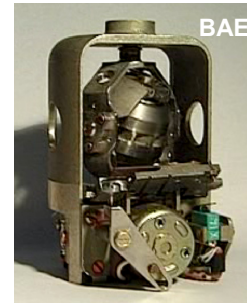
IBM

The IBM Active Protection System offers protection for common notebook accidents found in everyday life.



MEMS Gyroscopes

- Measure angular rotation rate using Coriolis effect
- Used extensively in aerospace applications
- Now for **automobile** (stability control) and **consumer** applications (camcorders, Segway, etc)
- MEMS allows measurement in places never before possible



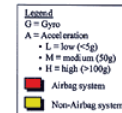
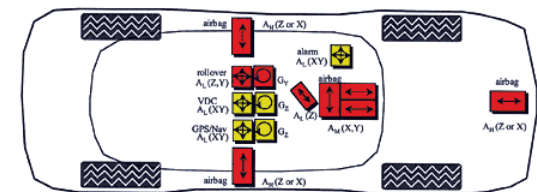
Traditional gyro



MEMS gyro



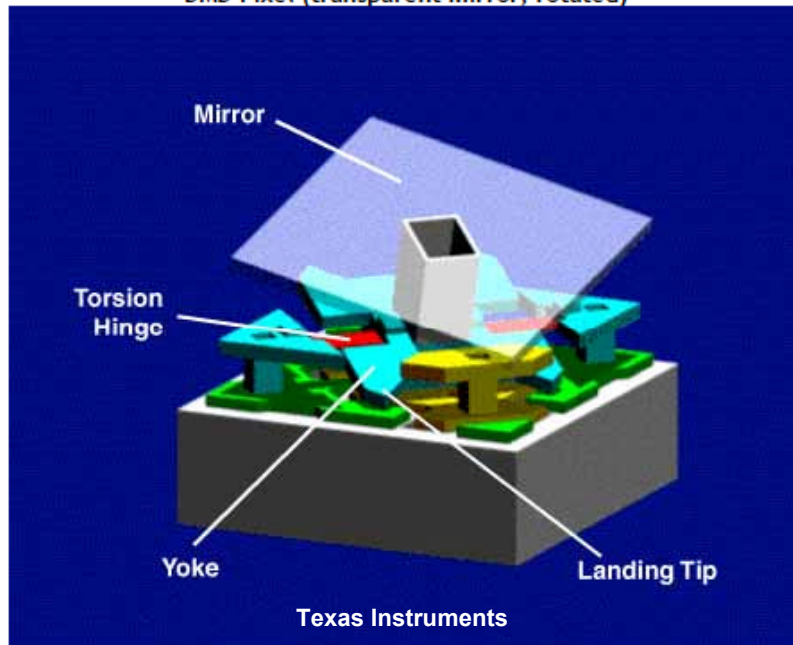
Analog Devices



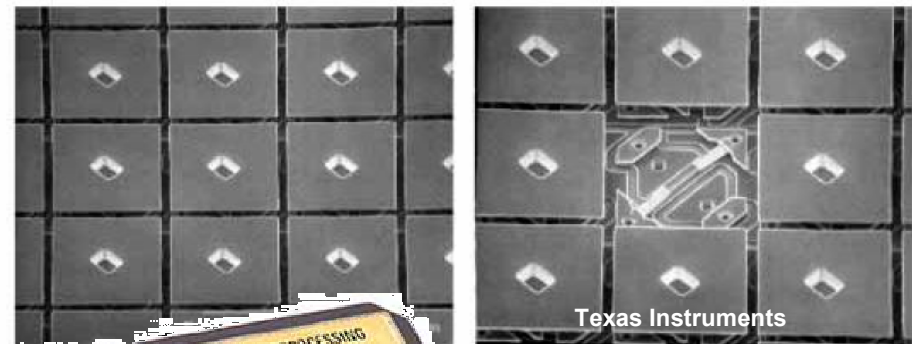
Digital Micromirror Arrays

- By Texas instruments in '87
- Used in video projectors, hi-end TVs, digital cinema, etc.
- State of the art - HDTV: $1920 \times 1080 = 2.7$ million mirrors

DMD Pixel (transparent mirror, rotated)



SEM photomicrographs of completed DMD chips after spacer removal



MEMS Advantages

MEMS advantages:

- Integrate the mechanical and electrical onto a single chip
- More functional, smaller, lighter, more reliable
- Drive down cost!
 - *Since volume production in '93, the ADXL 50 reduced auto airbag deployment system from \$100+ down to \$30.*
(source: Analog Devices)
- Small size/low cost enables new applications (laptop, mobile phone, etc)



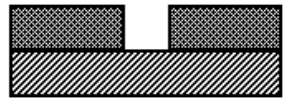
How are MEMS made?

- Microfabrication
- Packaging



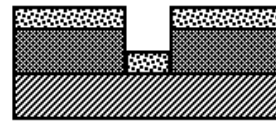
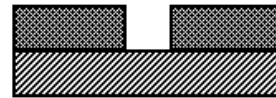
Microfabrication

Subtractive Process

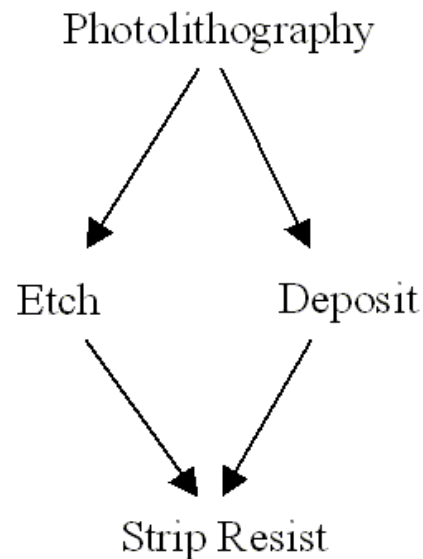


Pattern transfer
by etching

Additive Process



Pattern transfer
by lift off

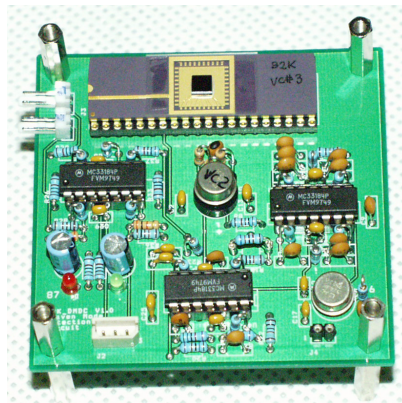
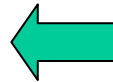
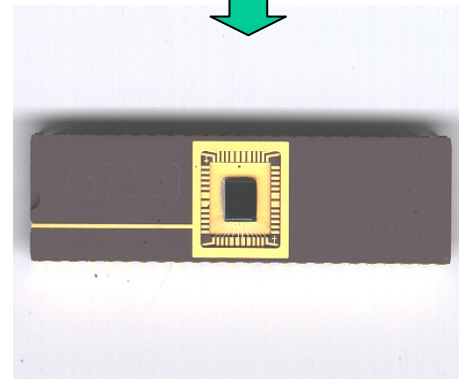
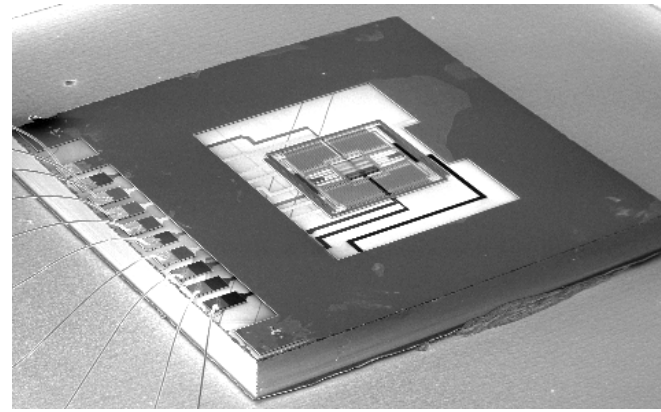
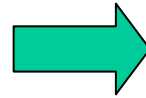
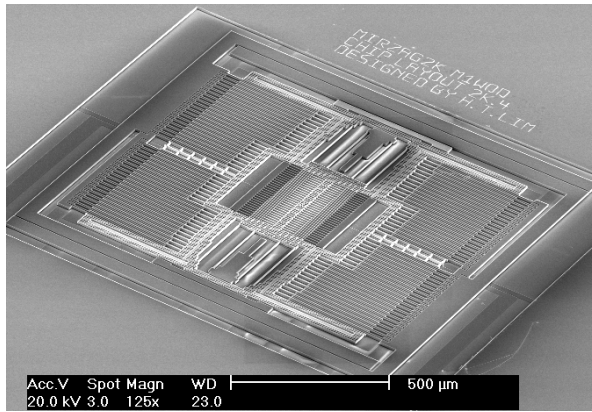


- By selectively etching away material or depositing new material on to areas not covered by protective patterns, a structure can be made.
- After multiple repetitions of these steps, a **Micromachine** is created.

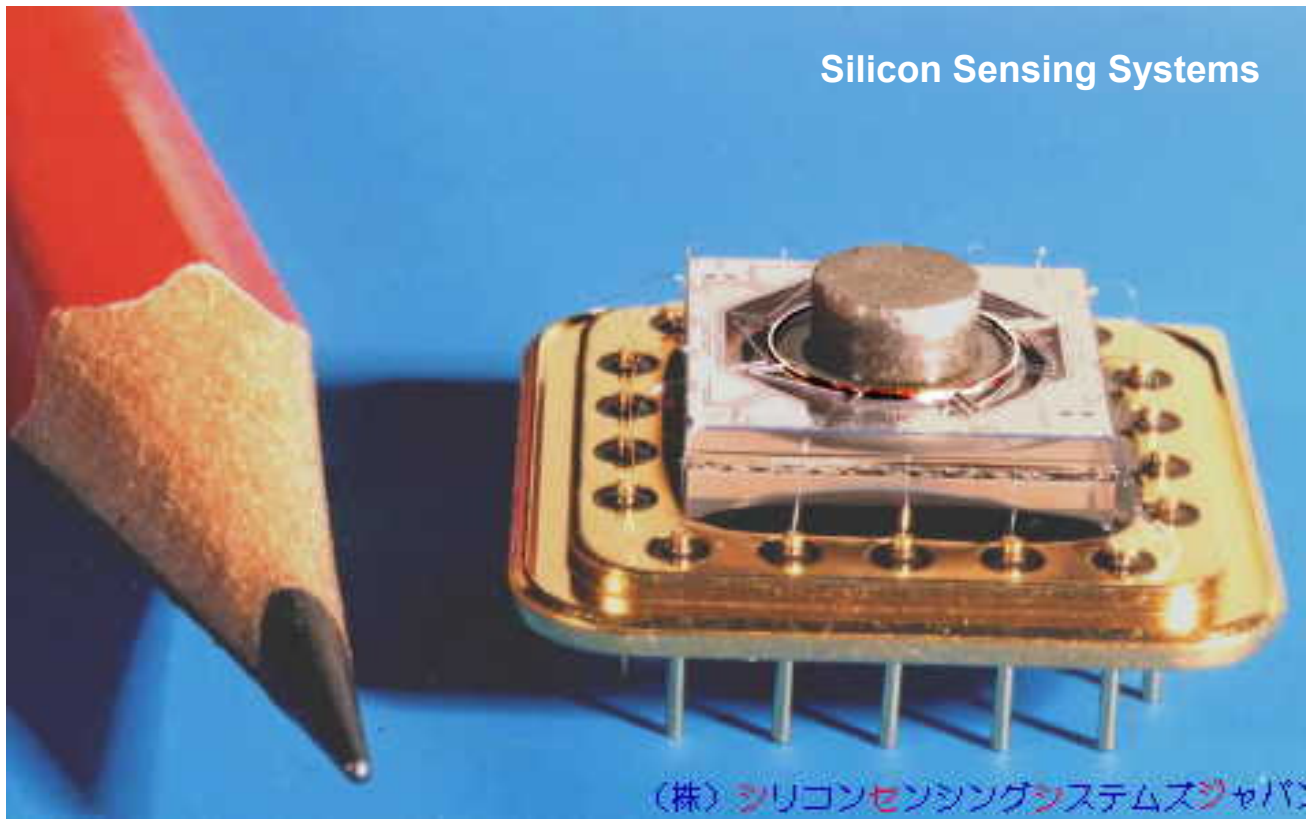
from <http://www.memsnet.org>



MEMS Packaging

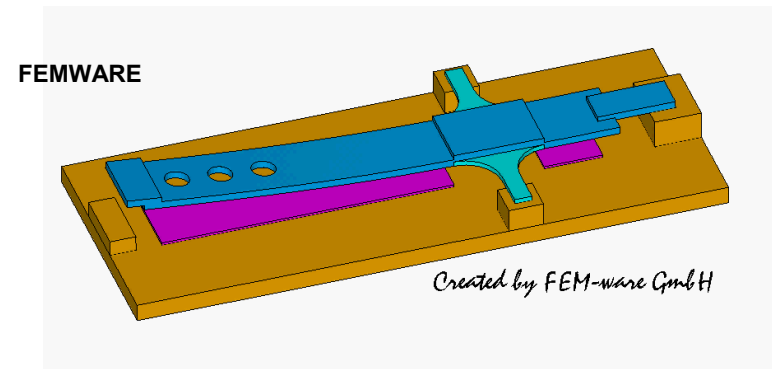
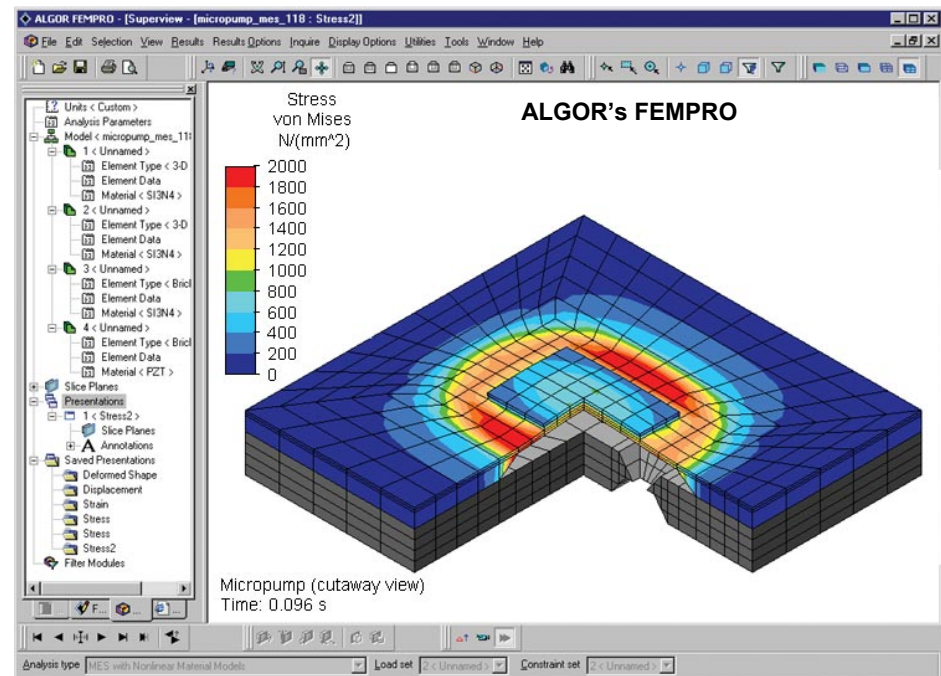


MEMS Packaging



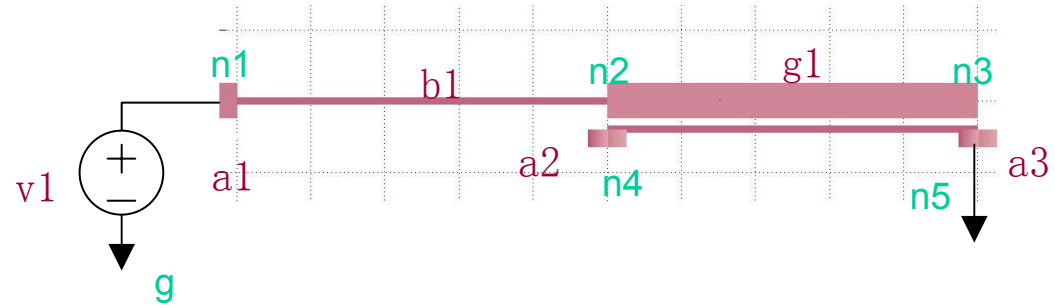
MEMS Simulation-1

- Finite Element Modeling –
 - Capability of tools growing
 - Slow but accurate
 - Break up model into thousands of small elements
 - Multi-domain:
 - Mechanical/ Electrical/ Thermal/ Electrostatic/ Magnetic, etc.



MEMS Simulation-2

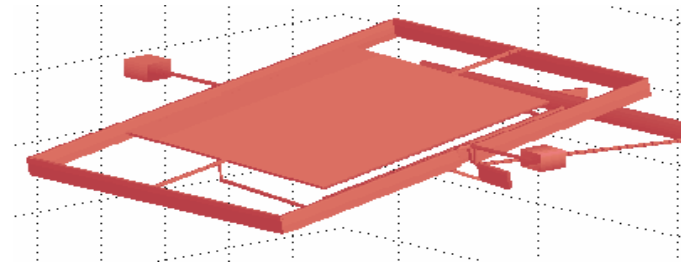
- Reduced Order Modeling –
 - ‘Spice for MEMS’
 - Modified Nodal Analysis
 - Orders of magnitude faster than FEM



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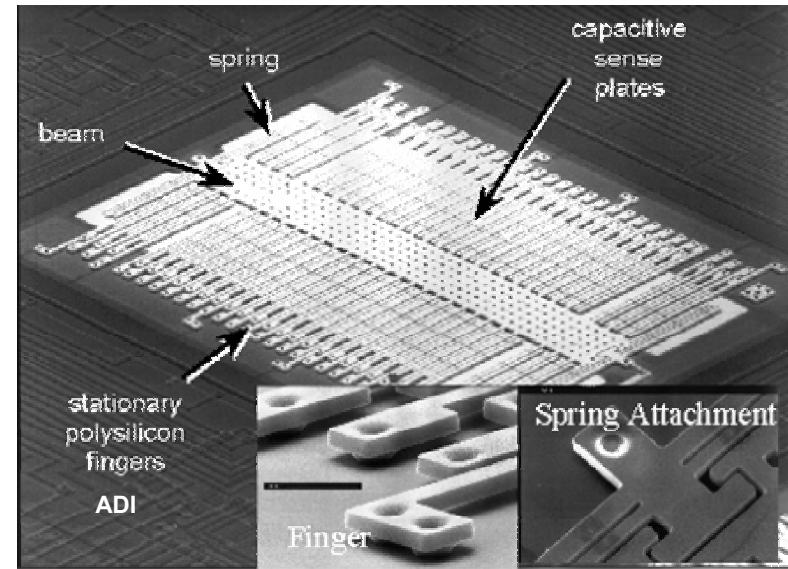
uses mumps.net
v1 Vsrc * [n1 g] [V=10]
e1 eground * [g] []
a1 anchor p1 [n1] [l=5e-6 w=10e-6 oz=180 R=100]
b1 beam2de p1 [n1 n2] [l=1e-4 w=2e-6 oz=0 R=1000]
g1 gap2de p1 [n2 n3 n4 n5] [l=1e-4 w1=1e-5 w2=2e-6 ...
gap=2e-6 R1=100 R2=100 oz=0]
a2 anchor p1 [n4] [l=5e-6 w=1e-5 oz=-90 R=100]
e2 eground * [n4] []
a3 anchor p1 [n5] [l=5e-6 w=1e-5 oz=-90 R=100]
e3 eground * [n5] []
    
```

- Caveat: Simulation is only as good as characterization!

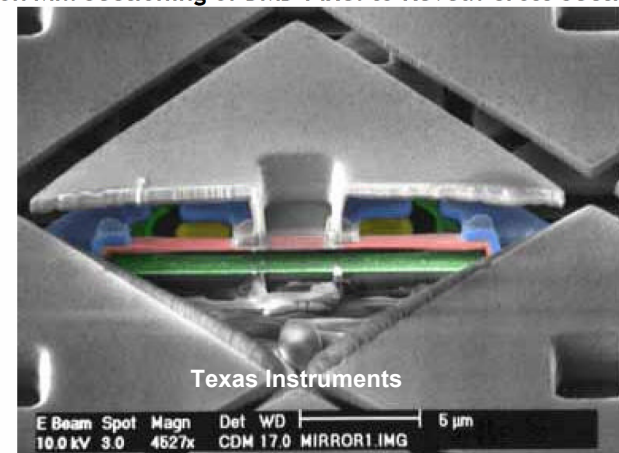


MEMS Device Design

- Still an immature field
- Designs are becoming very complex –
 - Multiple competing objectives
 - Multiple constraints from fabrication, safety, practical limits, etc
 - Dozens of variables
- Fabrication of prototypes a *slow, expensive* process

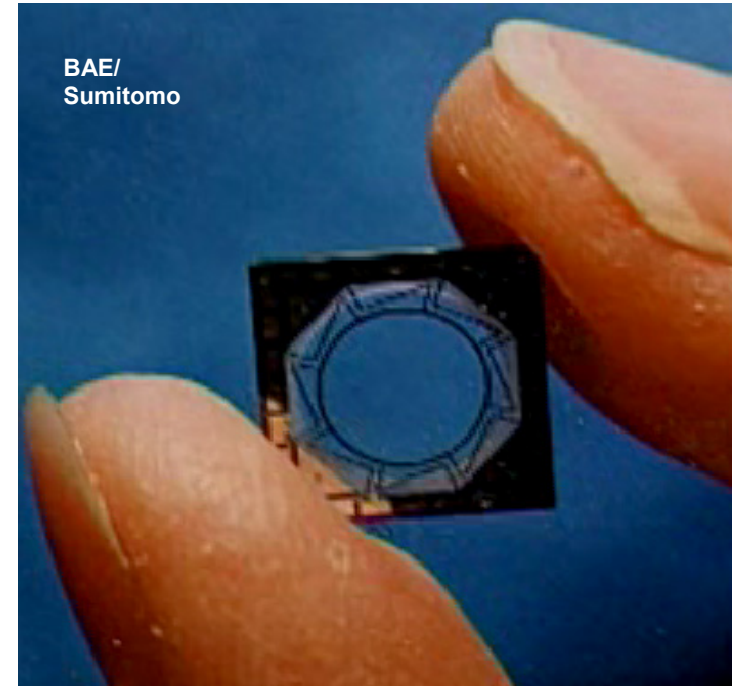


Ion Mill Sectioning of DMD Pixel to Reveal Cross Section

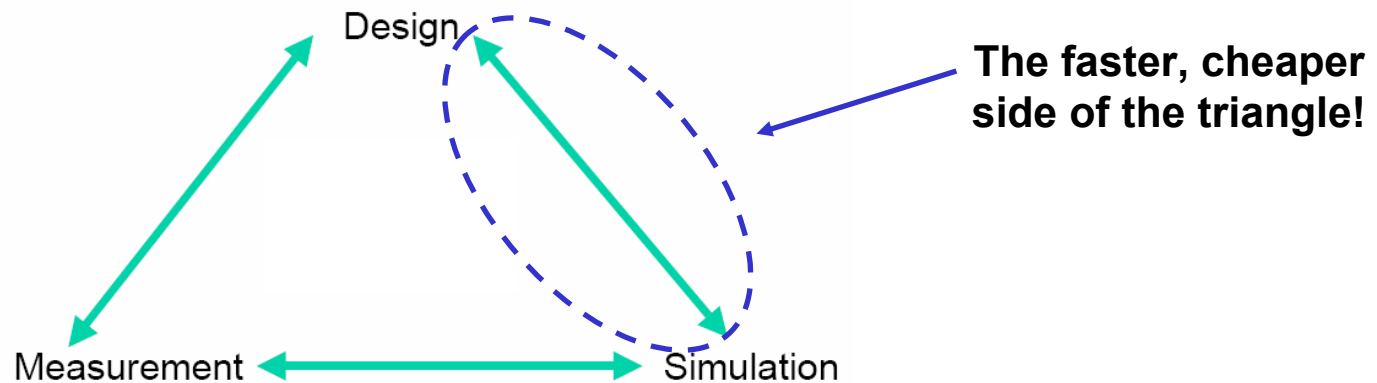


State of the Industry...

- Current design process very limited, simple
 - Hand calculations
 - FEM for confirmation
 - Grid Search (at best!)
 - Trial and error (fab/test/repeat)
- MEMS developing into competitive market
 - Applications/complexity growing rapidly
 - Inertial sensors, optical switches, etc already successful products
 - Improved design techniques required as market matures



The Solution: MEMS Design Synthesis Tools



- **What?** Automatically generate designs with a desired performance
- **Why?** Faster, more capable than manual design/hand calculations
 - More CAD = Less time in the fab = shorten design cycle = save \$\$\$!
 - Improved performance (multiple objectives)
 - Too many knobs to turn by hand!



The Solution: MEMS Design Synthesis Tools

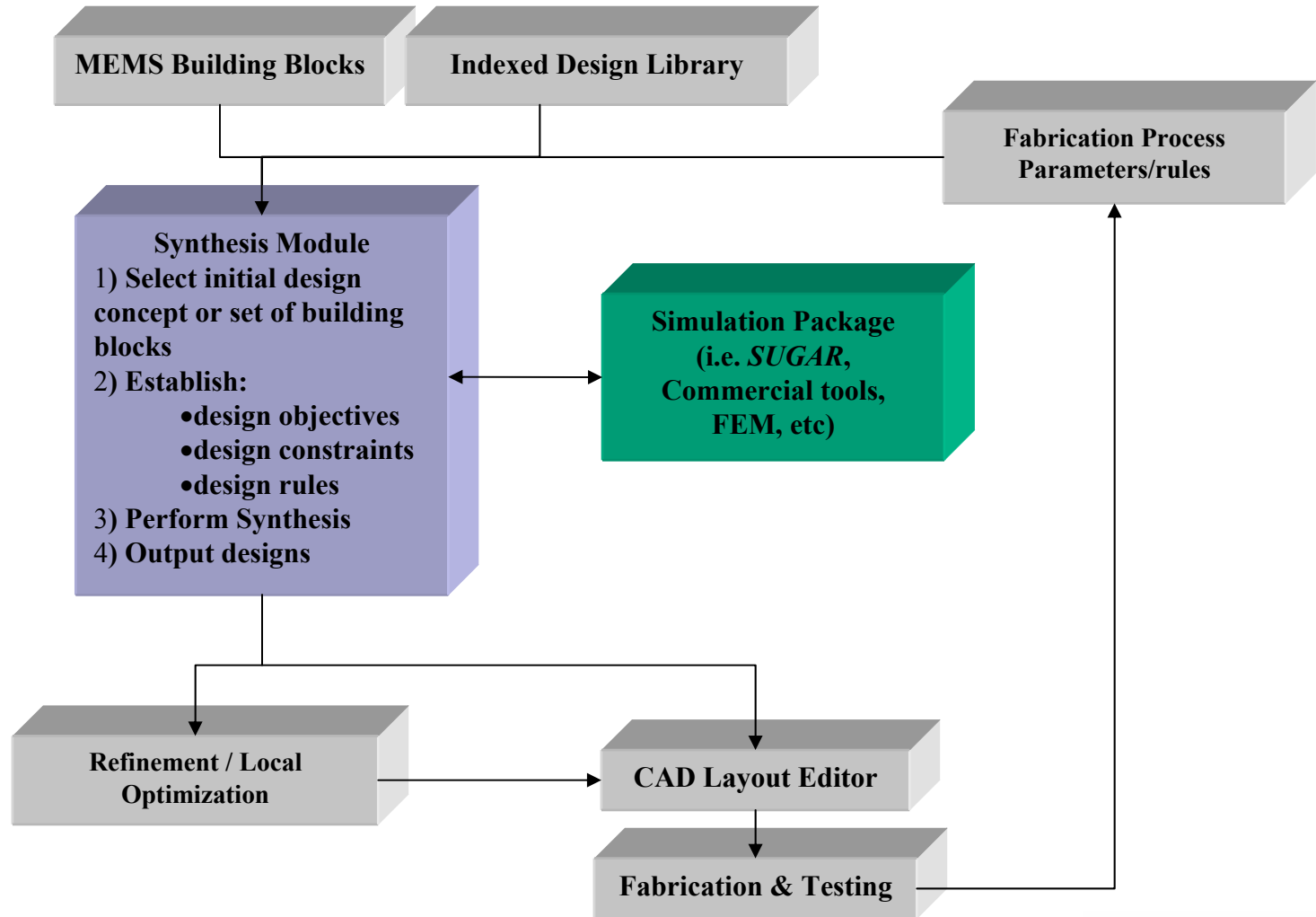
- **How?**

Use Evolutionary Synthesis/Optimization algorithms

- Can deal with
 - discrete variables
 - non-convex spaces
- Require only 'black box' evaluation from simulator
 - No gradients, no equations needed
- Configuration optimization + size optimization
 - Not just optimizing lengths and widths of components
 - Decide how many components, how they are connected

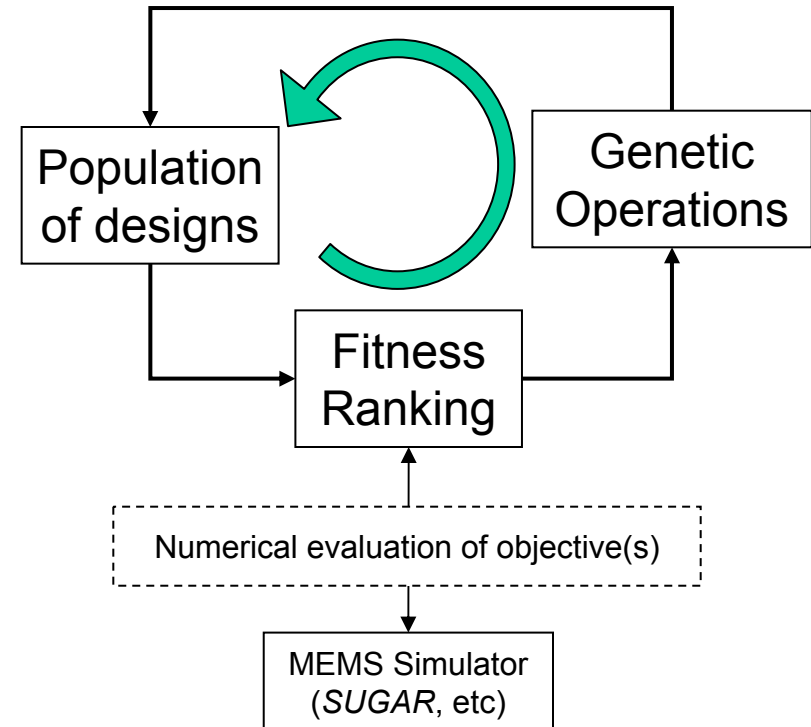


Proposed Architecture for MEMS Synthesis Tool



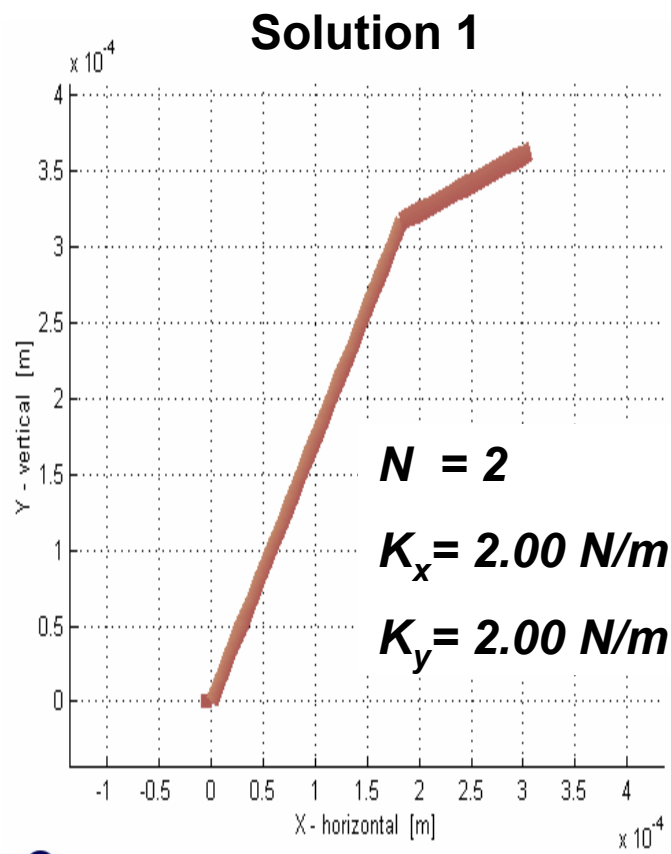
Use of EC for MEMS Design Synthesis

- Genetic Algorithms (GA)
 - Multiobjective GA (MOGA) balances multiple competing objectives
 - A population of “good” candidate designs returned at end of evolution
- Simulated Annealing (SA)



Simple Example – Synthesis of a MEMS Spring

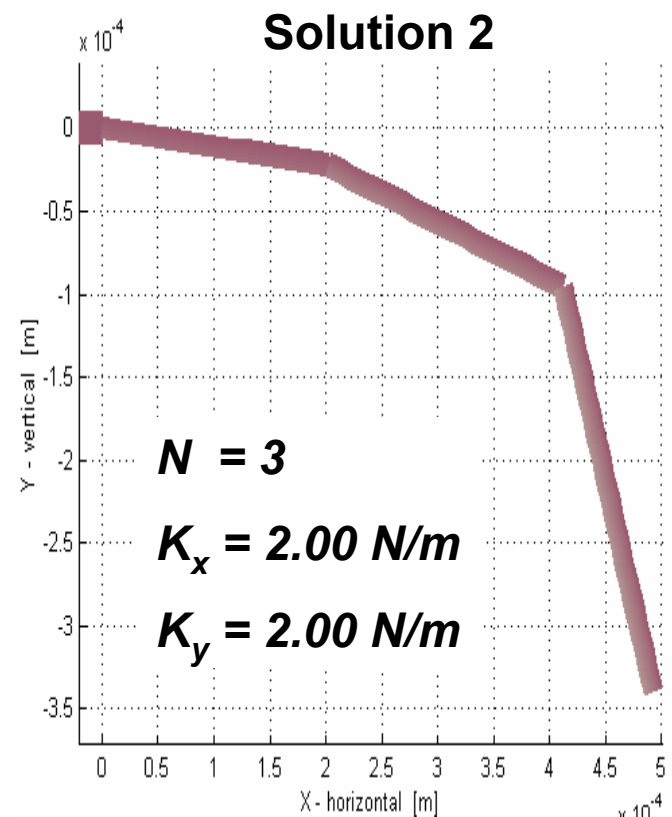
2 Objectives: $K_x = 2.00 \text{ N/m}$ $K_y = 2.00 \text{ N/m}$



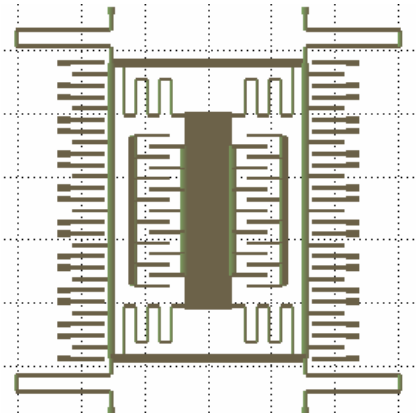
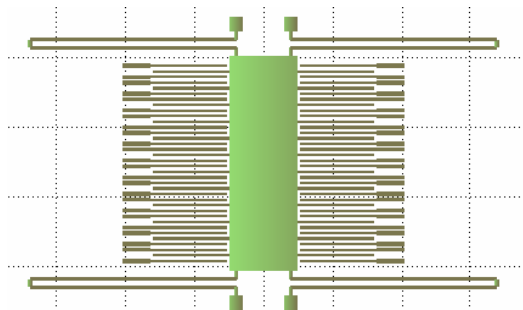
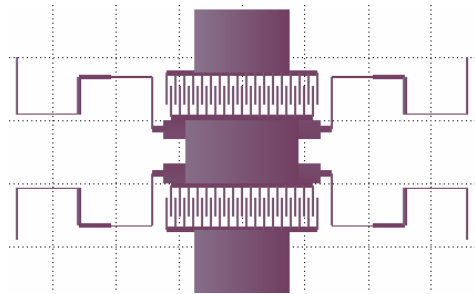
Genotype
Encoding:

l_1	w_1	θ_1
l_2	w_2	θ_2
l_3	w_3	θ_3
l_4	w_4	θ_4
\vdots	\vdots	\vdots
l_N	w_N	θ_N

Dimensions
of N beam
segments in
one spring



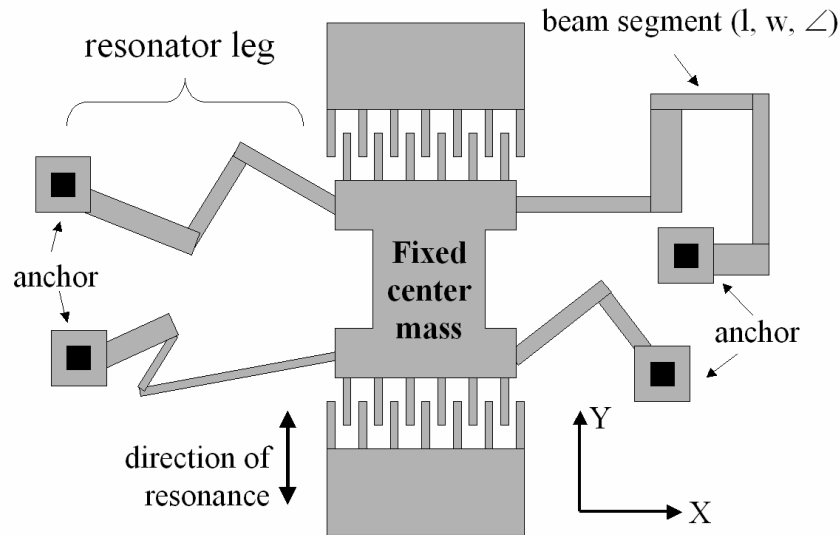
MEMS Application Examples



- Devices
 - Resonating Mass
 - Accelerometer
 - Gyroscopes
- Constraints
 - Symmetry?
 - Manhattan Angles?
- Potential Objectives
 - Resonant Frequency ω_r
 - Suspension Stiffness - K
 - Mode Shape
 - Device Area
 - Measurement Sensitivity

Resonating Mass Example

Design (phenotype):



- Mass suspended by springs, actuated by electrostatics
- Configuration of center mass fixed
- Legs variable

- Apply MOGA - two to four design objectives:

- ω_r
- Area
- K_y
- K_x

- Universal Constraints:

- Min/max beam dimensions
- Resonance in Y-direction

Encoding (genotype):

Geometry info for each of the q legs of design

$$\begin{bmatrix} \text{Leg}_1 \\ \text{Leg}_2 \\ \vdots \\ \text{Leg}_q \end{bmatrix}$$

$$\begin{bmatrix} l_1 & w_1 & \theta_1 \\ l_2 & w_2 & \theta_2 \\ l_3 & w_3 & \theta_3 \\ l_4 & w_4 & \theta_4 \\ \vdots & \vdots & \vdots \\ l_m & w_m & \theta_m \end{bmatrix}$$

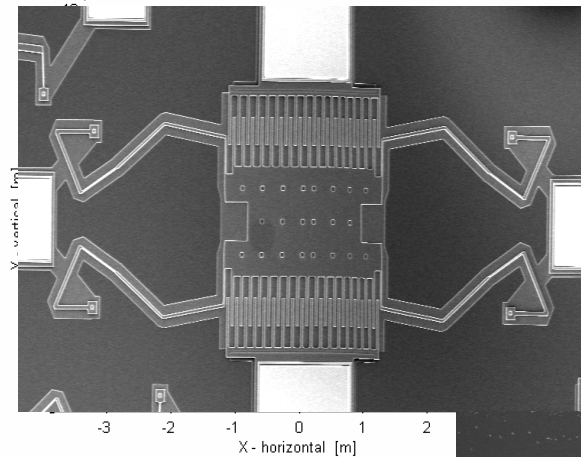
Dimensions of m beam segments in one leg

Synthesis Validation

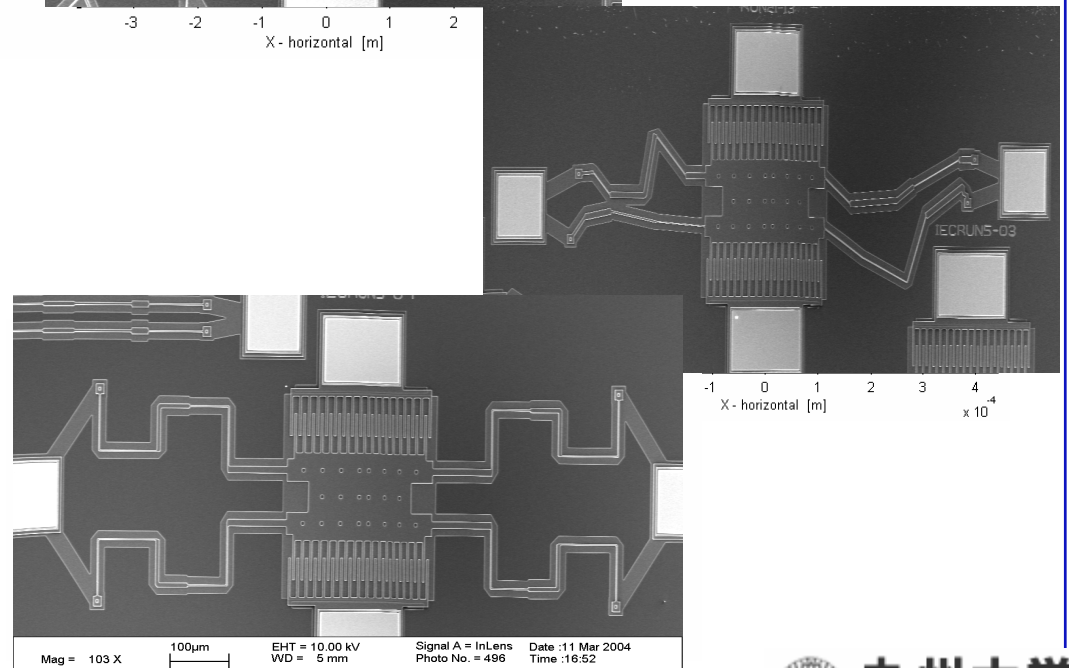
“Closing the Loop”

4 objective GA resonator synthesis and characterization:

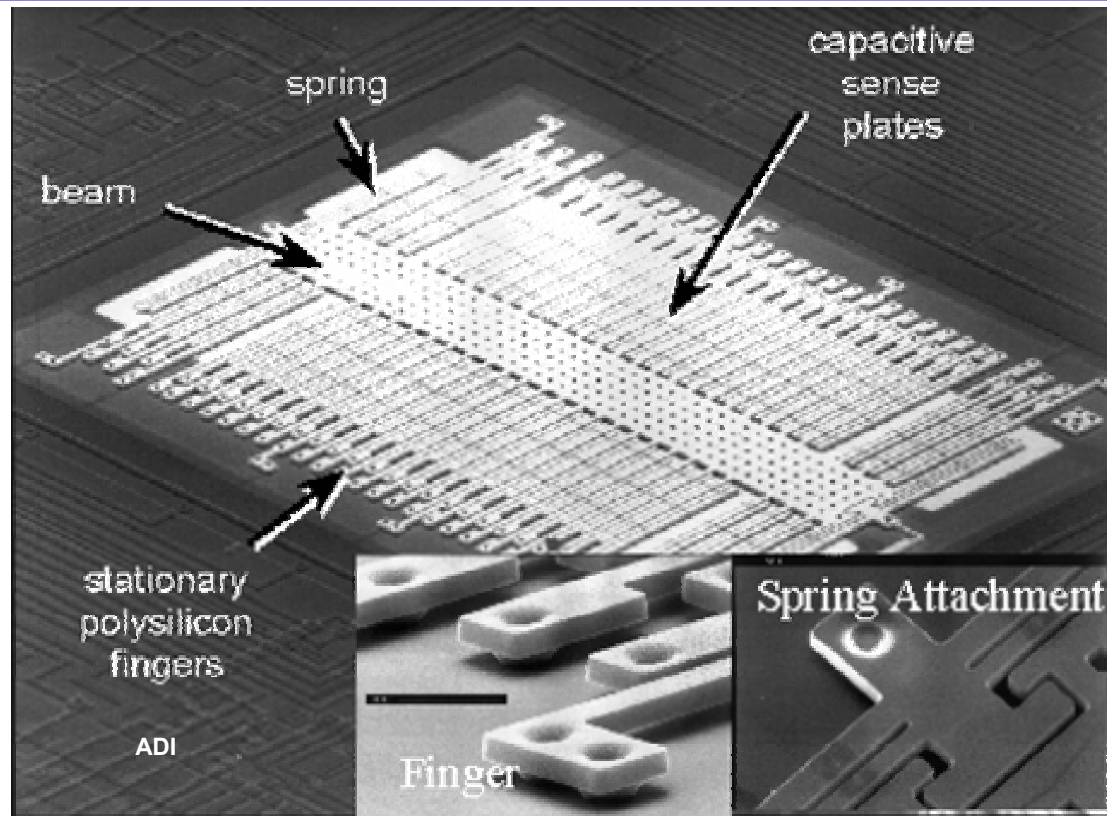
- Further characterizes MUMPs process
- Improved our understanding of impact of constraints and objectives on fabricated structures
- Validates this approach



- Goal $\omega_r = 10\text{kHz}$
- PolyMUMPs(run # 60)
- 36 unique designs
- 149 ω_r measurements
- Beam Overetch = $\sim 0.3 \mu\text{m}$
- $E = \sim 160 \text{ GPa}$
- Poly1 $\sigma_{\text{res}} > 5 \text{ MPa}$



ADXL-type Accelerometer Example

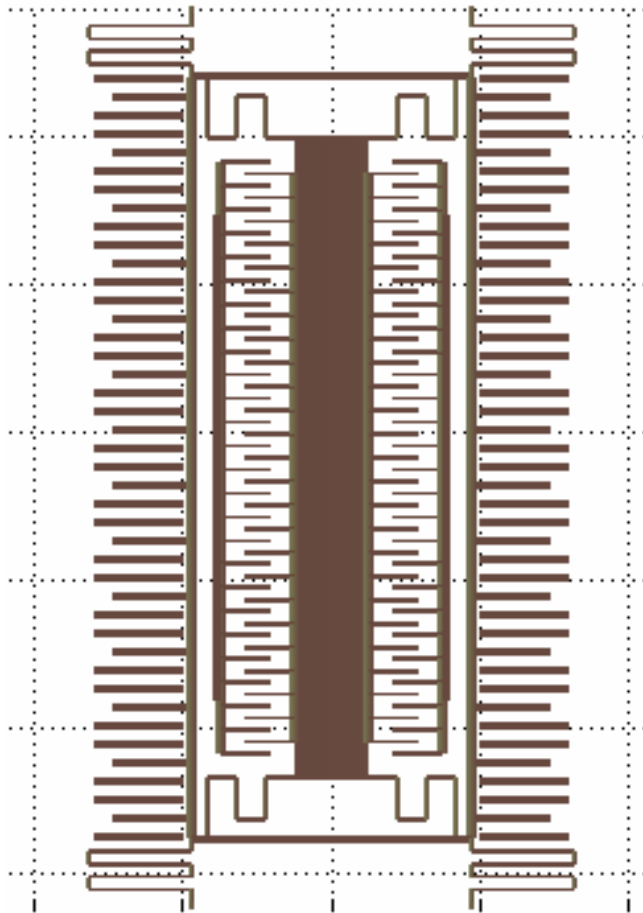


Please see Y. Zhang's "***Design Synthesis of Microelectromechanical Systems Using Genetic Algorithms with Component-Based Genotype Representation***" at *GECCO-06* for the latest research in MEMS Accelerometer Synthesis



Vibratory Rate Gyro Example

Similar to W. Clark or C. Acar style VRGs

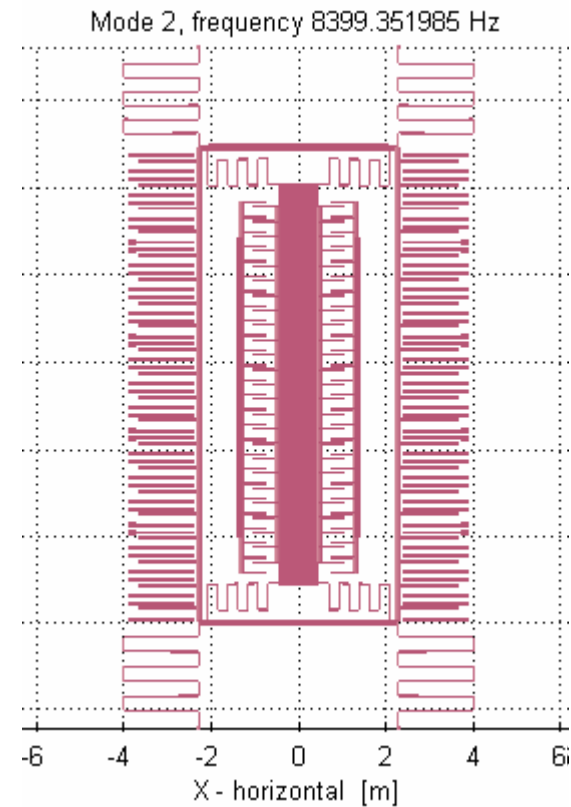
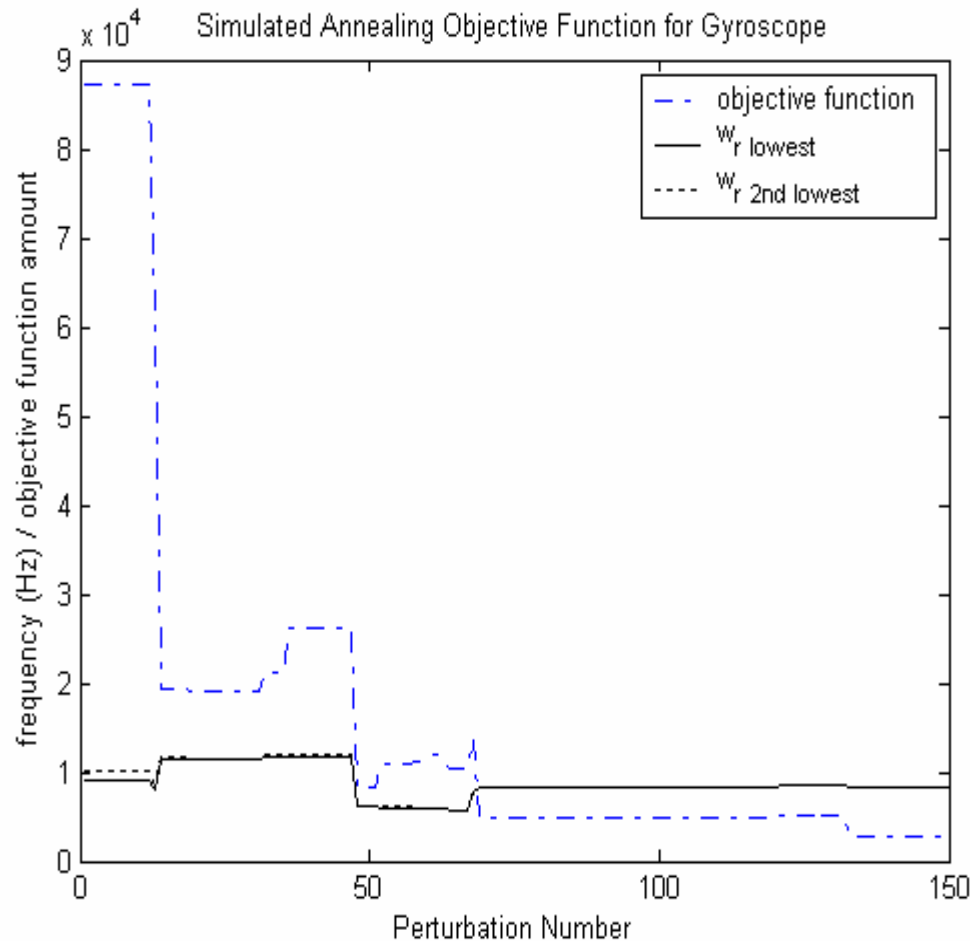


$\omega_{r \text{ goal}} = 10 \text{ kHz}$ $\Delta\omega_r = \text{minimized}$
 $k = \text{weighting factor} = 10, 100$

- Match 1st and 2nd resonance modes as closely as possible (@ 10 Hz)
- Use modeshape to verify direction of resonance (from eigenvectors)
- Simulated Annealing objective function:

$$F(x) = \left| \omega_{r\text{-lowest}} - \omega_{\text{goal}} \right| + k \left| \omega_{r\text{-lowest}} - \omega_{r\text{-2nd_lowest}} \right|$$

Example Gyro Synthesis Output



Issues with EC for MEMS Synthesis

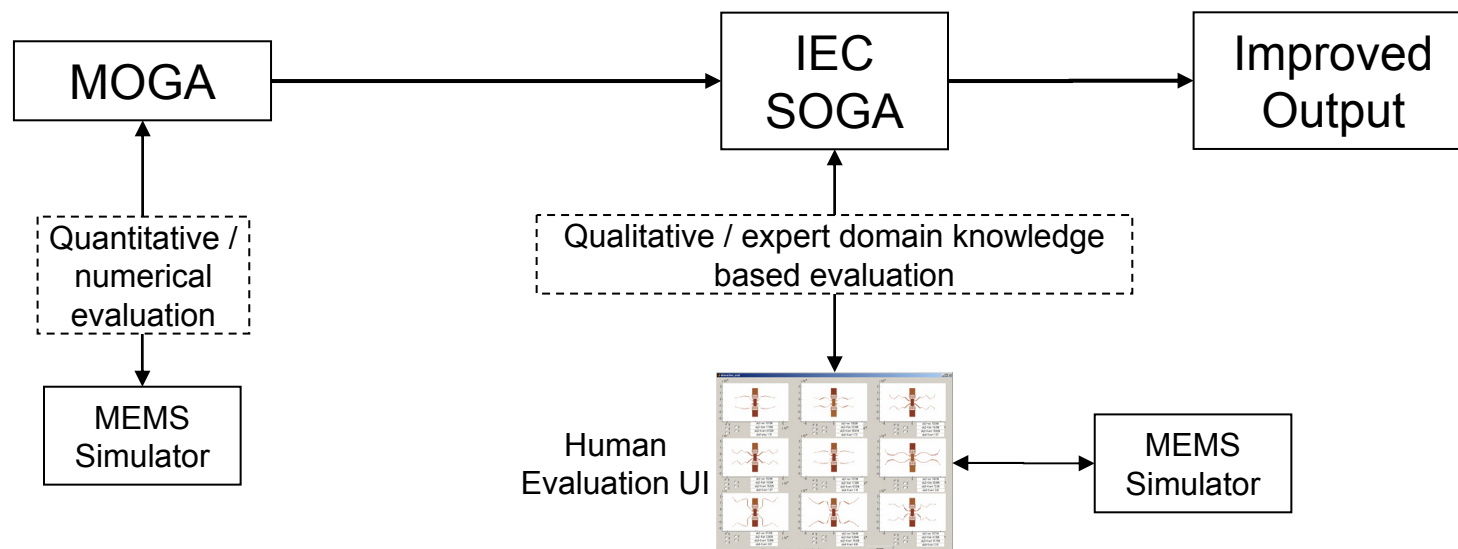
- GAs play by the rules you give them, whether they are complete or not.
 - *It will find the holes in your formulation!*
- There are limitations in simulators
 - Non-simulatable phenomenon can not be included in fitness ranking.
- Not every rule or guideline can be turned into a line of code...

- Our solution:
 - Use ***Interactive Evolutionary Computation (IEC)***
 - based on human's evaluation of fitness
 - Originally developed for aesthetic or sensory design
 - Human interaction allows 'implied' constraints
 - Expert domain knowledge / experience can guide the evolution process.



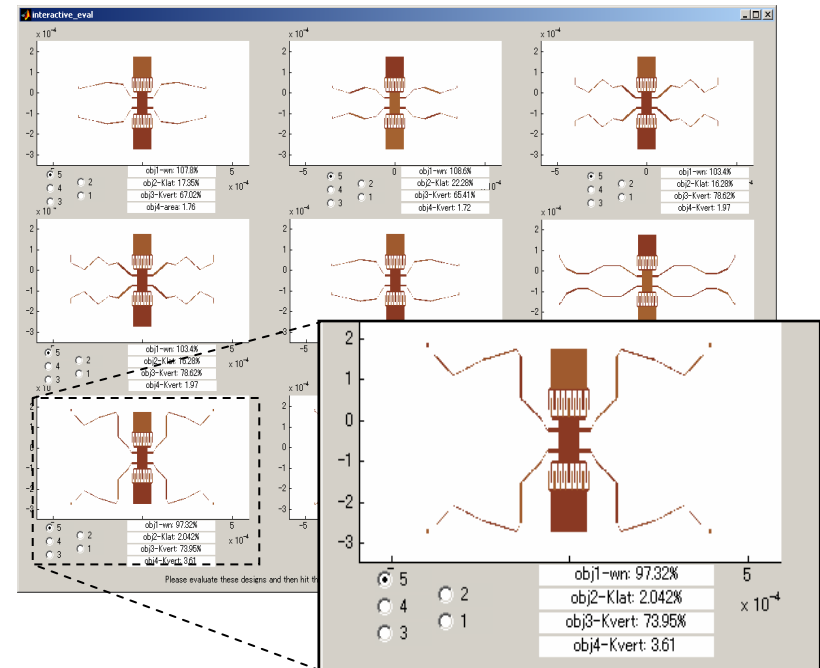
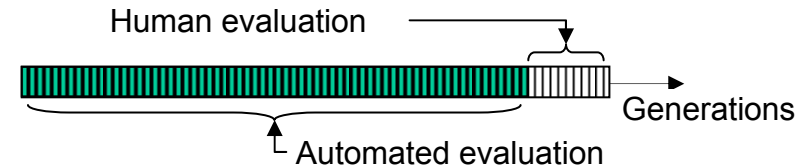
IEC for MEMS Synthesis 1:

- First iteration: MOGA+IEC
- Take output of automated MOGA and do single objective GA (SOGA) using human evaluation.
- Human can 'hone' output.



IEC for MEMS Synthesis 1:

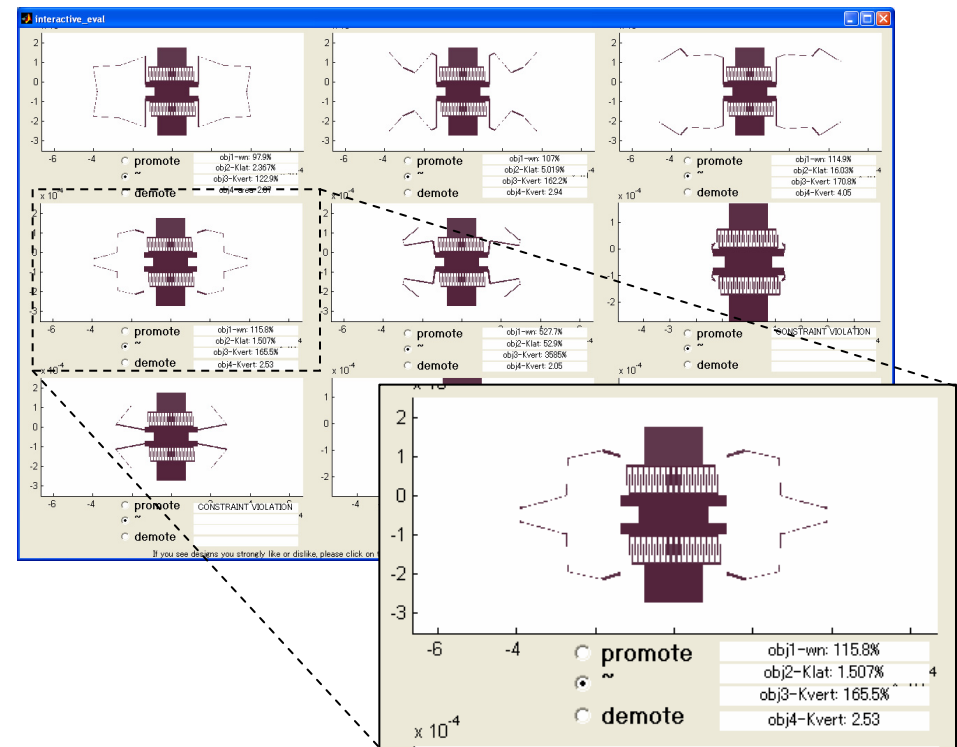
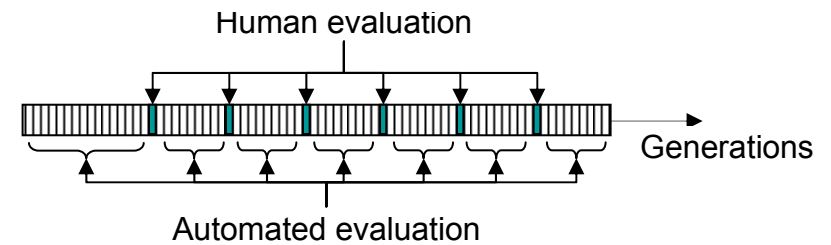
- Human shown design topology AND simulation results
- Human gives evaluation based on their expert knowledge/ experience
- Constraints/ Objectives applied by human need not be pre-determined or static.



- User study shows significant improvement using MOGA+IEC vs. MOGA alone

IEC for MEMS Synthesis 2:

- Alternate IEC implementation:
 - Supervisory: Better combination of expertise of human with tirelessness of computer
 - Intersperse human into automated EC
 - Change from 'absolute score' to relative (+ / ~ / -)
 - use Pareto Rank shifting
 - Human effort reduced significantly
 - Produces better designs than automated EC alone.



Industry Reaction to Automated Synthesis for MEMS

- Resistant to automated synthesis
 - Not Programmers!
 - ...usually are fab experts, not designers.
 - Many applications are beyond the scope of practical simulation tools
 - Want more direct interaction with problem
 - Don't like being hands-off
 - Our current IEC is not enough!
 - Can't change specific variables, etc
- Need to find a middle ground between automated and manual:
 - 'Computational Steering' / Interactive Design Synthesis



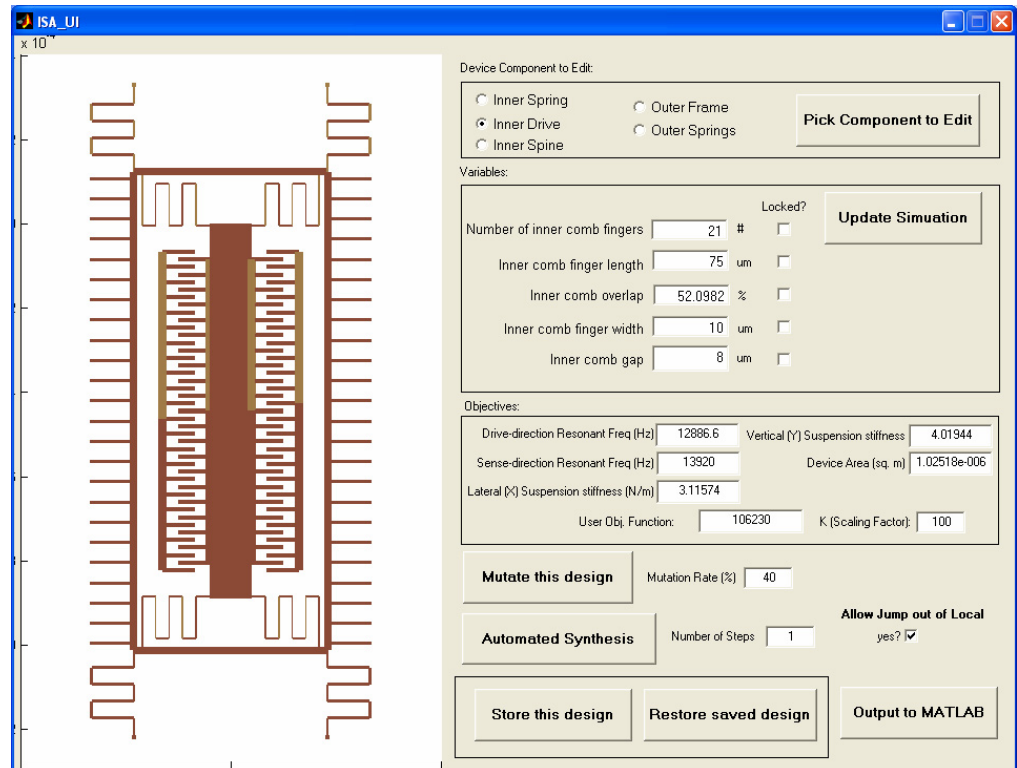
Proposed Solution

- A MEMS CAD GUI for design modification, simulation and synthesis
- Offer simple evolutionary synthesis capability:
 - Random Walk
 - Simulated Annealing (SA)
- Closer to Parmee's approach to IEC than to our traditional one.
 - Parameters of automatic EC search are controlled by human interactively.



Interactive Evolution GUI:

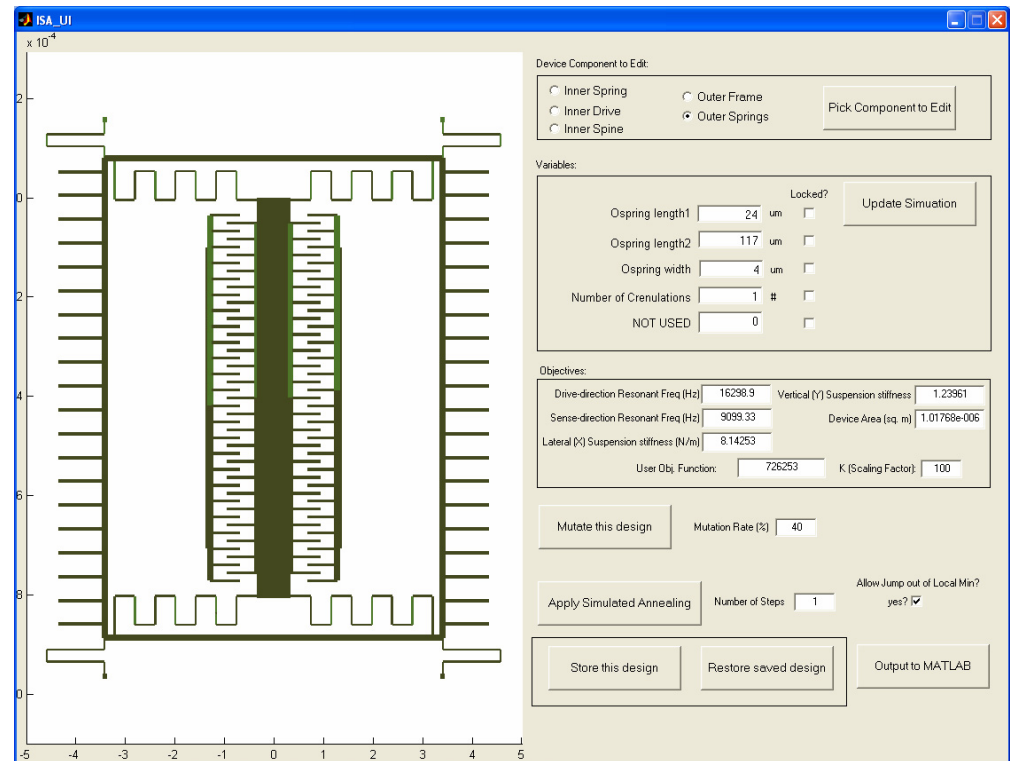
- Interactive CAD Simulator
 - Independently adjust desired variables
 - Get performance #'s from simulator package
- Synthesis Tool
 - Single mutation step
 - Multi-step Random Walk or SA
 - User can lock desired variables
 - Reduces search space



Can be used as fully manual parameter tuning or fully automated synthesis or somewhere in between

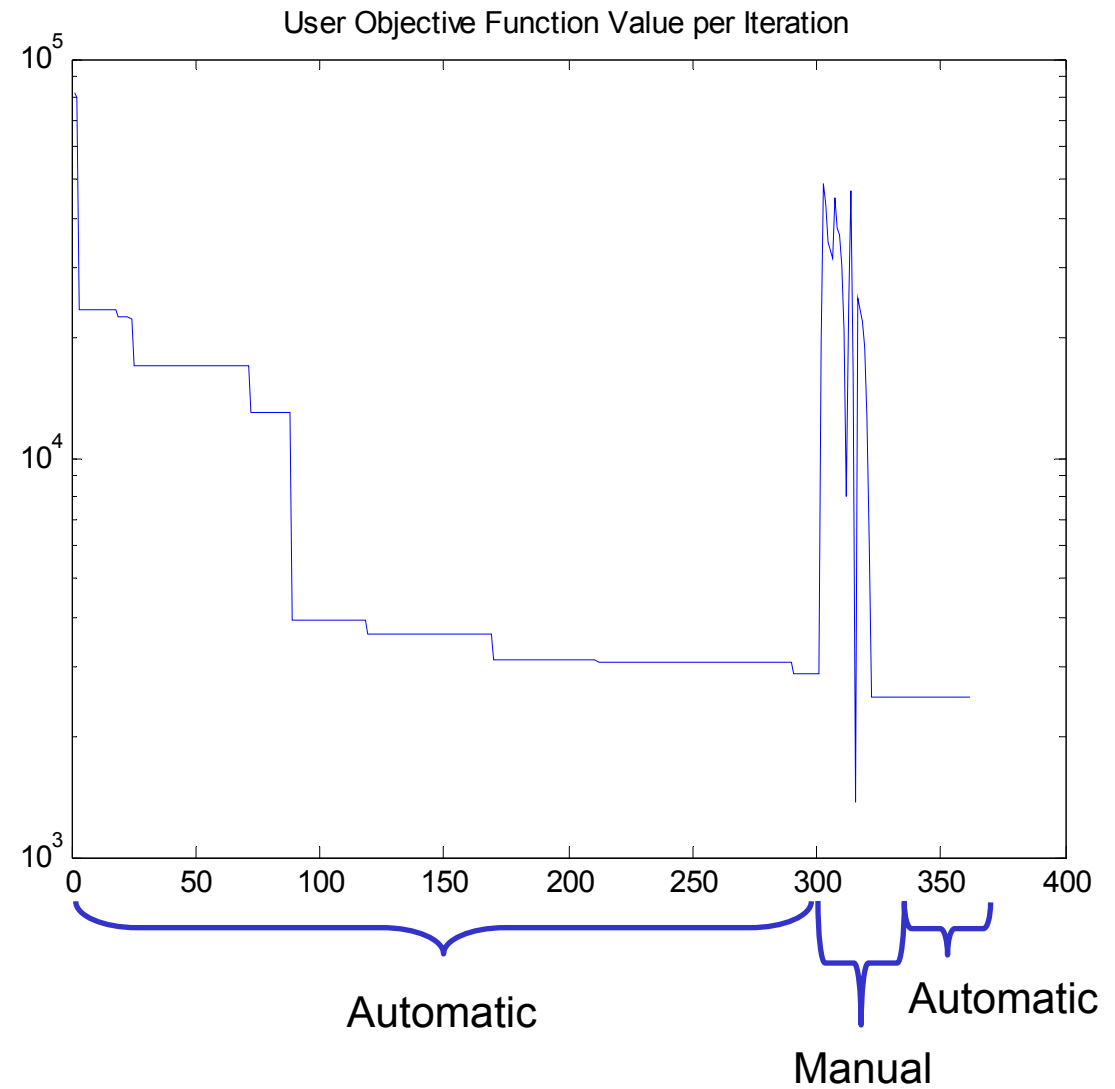
Interactive Evolution GUI:

- Generality / flexibility important.
 - Simple, standardized data structure
- Interface via MATLAB with any simulation package
 - SUGAR, FEA, etc
- User need only create functions to interface with simulator only.



Interactive Evolution GUI: Results

- Able to find designs
 - Use pattern depends on user
 - Manual → Automatic?
 - Automatic → Manual?
 - Hard to quantify this performance!
- Process of using this tool also helps provide engineer with design experience / knowledge



Conclusions

- Summary
 - MEMS an important new field in need of design tools
 - Interactive evolution based MEMS synthesis introduced
 - Based on Industry feedback / lack of interest –
 - Search for proper balance between automatic and completely manual design approach needed
 - Keeping it flexible and generic is key!
- Further work
 - Alternate approaches?
 - Additional features?
 - Try to get industry to adopt these methods.



Questions? Acknowledgements

- For more information
 - Please see <http://me.berkeley.edu/~raffi> for PDFs of our papers
- BEST LAB UC Berkeley – best.berkeley.edu
 - Professor Alice Agogino, Ying Zhang, Ningning Zhou
- Takagi Lab – Kyushu University
 - Professor Hideyuki Takagi
- <http://bsac.berkeley.edu/cadtools/sugar>

- Acknowledgements
 - Japanese Society for the Promotion of Science
 - US National Science Foundation

